

#5
CIAU 1765

PATENT

3-4-c

Linda
B.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Svirchevski et al.

Application No: 09/336,401

Filed: June 18, 1999

For: POST-PLASMA PROCESSING WAFER
CLEANING METHOD AND SYSTEM



Group Art Unit: 1765

Examiner: Unassigned

Atty. Docket No: LAMIP109

Date: February 18, 2000

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on February 18, 2000.

Signed: _____

Kay Harlow

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §§1.56 AND 1.97(c)

Assistant Commissioner for Patents
Box: IDS
Washington, DC 20231

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0805 (Order No. LAMIP109).

Respectfully submitted,
MARTINE PENILLA & KIM, LLP

Albert S. Penilla, Esq.
Reg. No. 39,487

710 Lakeway Drive, Suite 170
Sunnyvale, CA 94086
Telephone: (408) 749-6900

BEST AVAILABLE COPY

RECEIVED
FEB 24 2000
TC 1700 MAIL ROOM